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INFORMATION DISCLOSURE STATEMENT (Use several sheets if necessary)				APPLICANTS Masahiro SAKURADA et al.			
				FILING DATE November 30, 2004			

U.S. PATENT DOCUMENTS						
EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	

FOREIGN PATENT DOCUMENTS						
DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB CLASS		
<i>F.H.</i> 1 WO 97/21853 w/abstract	06/19/1997	WIPO				
<i>F.H.</i> 2 JP A 2000-53486 w/abstr.	02/22/2000	Japan				
<i>F.H.</i> 3 JP A 5-43385 w/abstr. + trans.	02/23/1993	Japan				
<i>P.H.</i> 4 JP A 9-227286 w/abstr. + trans.	09/02/1997	Japan				

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)		
<i>F.H.</i>	5	Voronkov, "The Mechanism of Swirl Defects Formation in Silicon," Journal of Crystal Growth, Vol. 59, No. 3, pp. 625-643, 1982
<i>P.H.</i>	6	Dupret et al., "Global modeling of heat transfer in crystal growth furnaces," Int. J. Heat Mass. Transfer, Vol. 33, No. 9, pp. 1849-1871, 1990
<i>P.H.</i>	7	Vizman et al., "Three-dimensional numerical simulation of thermal convection in an industrial Czochralski melt: comparison to experimental results," Journal of Crystal Growth 233, pp. 687-698, 2001

EXAMINER <i>[Signature]</i>	DATE CONSIDERED <i>8/2/06</i>
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Examiner: Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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